

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Docket No.: VLSI-3402

I hereby certify that this transmittal of the below described document is being deposited with the United States Postal Service in an envelope bearing First Class Postage and addressed to the Assistant Commissioner for Patents, Washington, D.C., 20231, on the below date of deposit.			
Date of Deposit:	07/09/01	Name of Person Making the Deposit:	Anthony Chou
		Signature of the Person Making the Deposit:	<i>Anthony Chou</i>

In re Application of:

Inventor(s): Rao Venkateswara Annapragada

Application No.: 09/544,804

Filed: 04/07/00

Title: A METHOD OF IMPROVING ADHESION OF CAP OXIDE TO NANOPOROUS SILICA FOR INTEGRATED CIRCUIT FABRICATION

**Assistant Commissioner for Patents  
Washington, D.C. 20231**

CONDITIONAL PETITION FOR EXTENSION OF TIME

This conditional petition is being filed along with the accompanying DIVISIONAL and provides for the possibility that applicant has inadvertently overlooked the need for a petition and fee for extension of time.

**Conditional petition for extension of time**

If any extension of time for the accompanying response is required, applicant requests that this be considered a petition therefor.

**Status**

This application is on behalf of

- ☒ other than a small entity  
☐ a small entity

A verified statement:

- ☐ is attached  
☐ is already filed

- [x] The Commissioner is hereby authorized to charge any additional fees associated with this communication or credit any overpayment to Deposit Account No.: 23-0085.  
 A duplicate copy of this authorization is enclosed.

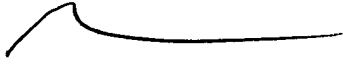


Please direct all correspondence concerning the above-identified application to the following address:

**WAGNER, MURABITO & HAO LLP**  
Two North Market Street, Third Floor  
San Jose, California 95113  
(408) 938-9060

Respectfully submitted,

Date: 7/9/01

By:   
John P. Wagner, Jr.  
Reg. No. 35,398